

**e-Diagnostic Working Group Meeting Attendance - September 20, 2000  
International Sematech**

<b>Company</b>	<b>Name</b>	
Advanced Energy Industries	Bill	Shade
Adventa Control	Richard	Beaver
Adventa Control	Carl	Fiorletta
AMD	Michael	Borman
AMD	Eric	Christensen
AMD	Greg	Nelson
Applied Materials	Shay	Assaf
Applied Materials	Juan	Bocanegra
Applied Materials	Neil	Frank
ASYST Technologies	Chris	Barbazette
ASYST Technologies	Paul	Steele
AvantCom Network	Bob	Chamberlain
AvantCom Network	Subhash	Patankar
Axcelis Technologies Inc.	Frank	D'Andrea
Axcelis Technologies Inc.	Hans	Sundstrom
Axcelis Technologies Inc.	Han	Zhang
Brooks Automation	Chris	Brandson
Canon	Arthur	Luk
Domain Logix	Lawrence	Eng
Electroglas, Inc.	Howard	Ignatius
General Electric	Ujjal	Basu
General Electric	Tim	Johnson
HP	Glen	Ingebrigtsen
IBM	William	Ramus
IBM/ISMT	John	Pace
Intel	David	Bloss
Intel	Jonathan	Clemens
Intel	Kacey	Crowley
Intel	Wane	Dompier
Intel	Piero	Fioravanti
Intel	James	Martin
Intel	Anant	Raman
International Sematech	Scott	Kramer
International Sematech	Carol	MacNaughton
International Sematech	Peter	Marrone
International Sematech	Mary	Marsden
International Sematech	Margaret	Pratt
International Sematech	Mike	Sigman
International Sematech	Harvey	Wohlwend
IPC	Nicole	Richter-Ulmer
IPC	Gerhard	Rupp
KLA-Tencor	Roger	Eastvold
KLA-Tencor	Michael	Locy
KLA-Tencor	Nick	Nikolic
KLA-Tencor	Anjali	Sridhar
Kokusai	Tom	Marrone
Lam Research Corporation	Jacques	Matteau
Motorola	Don	Hartman
Nikon Precision, Inc.	Sean	McNamara

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<b>Company</b>		<b>Name</b>
Nikon Precision, Inc.	John	Wiesner
Novellus	Tomas	Garley
PRI Automation, Inc.	Larry	Dulmage
Schlumberger	Claude	Baudoin
Schlumberger	Robert	Brandom
Schlumberger	Chris	Stambaugh
Semy Engineering	Muthu	Ramalingam
SISA	John	Ellis
STM/ISMT	Olivier	Louveau
SVG	Peter	DelMastro
Symphony Systems	Keith	Bennett
Teradyne Inc	Frank	Kennedy
Teradyne Inc	Gerry	McMahon
Tokyo Electron America, Inc.	Lou	Steen

*Information Based on Registered Sign-in 9/20/2000*

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Company	Name
Advanced Energy Industries	Fred Desantis
Adventa Control Technologies	Carl Fiorletta
AMD	Elfido Cross
AMD	Mikkel Lantz
AMD	Anthony Manti
AMD	Greg Nelson
Applied Materials	Shay Assaf
Applied Materials	Ben Henniges
Applied Materials	Sam Sher
ASML	Doreen Chavarria
AvantCom	Chris Saso
Brookside Software	Dave Youlton
Cymer, Inc.	Joe D'Esopo
Cymer, Inc.	Petar Maroevic
Cymer, Inc.	Sharnaz Motakef
Domain Logix	Jim Macek
Domain Logostics	Charles Baylis
EquipNet	Mike Biche
EquipNet	Peter Szasz
GaSonics	Connell Yuk
GKS	Jay Newman
Graphco Technologies	Herman Colbert
Graphco Technologies	Chris Toma
Helix Technology Corp.	Ted McIntyre
Helix Technology Corp.	David Arthur
HP	Glen Ingebrigtsen
IBM	Bob Wiggins
Infineon	Ken Dye
Intel	Diane Barkley
Intel	Bonnie Bennett
Intel	Dave Bloss
Intel	Gary Smith
International Sematech	Sandi Churchill
International Sematech	Don Erm
International Sematech	Randy Goodall
International Sematech	Peter Marrone
International Sematech	Mary Marsden
International Sematech	Mike Sigman
International Sematech	Harvey Wohlwend
International Sematech	Brad Van Eck
IPC	Nicole Richter-Ulmer
IPC	Gerhard Rupp
IPC	Christopher Link
Kinetics Applications & Technology	Gary Frank
KLA-Tencor	Paul McGuire
KLA-Tencor	Michael Locy
KLA-Tencor	Nick Nikolic
KLA-Tencor	Alan Weber
Kulicke & Soffa Industries	Mike Vinson
Lam	Farah Bashti
Lam	Andrew Lui
Millipore Corporation	Christopher Wargo
Motorola	Frank Jenkins

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Company	Name
Murata	Ron Denison
NEC	Michio Honma
NG Technology	Tai-Sheng Liu
Nikon	Hajime Nakamura
Nikon	Noriyasu Oshima
Nikon	Katsuhiko Yamaguchi
nLine	Bob Bryant
nLine	Philip Schumaker
Novellus	Paul Korff
OSI Software	Jim O'Rourke
Praxair	Nick Farrah
Praxair	Malcolm Grierson
PRI Automation	Tom Baum
PRI Automation	Doug Scott
RF Solutions	Russell Funk
Rudolph Technologies	Greg Wolf
Schneider Electric	Steve Ewankowich
Selete	Shigeru Kobayashi
Semy Engineering	Kevin Dimond
Si Automation	Christophe Fraysse
Si Automation	Abel Mikati
Simon Technology	Eugene Lin
Sumitomo Eaton Nova Corp.	Masao Nojiri
Symphony	Jean-Yves Bancilon
Symphony	Doug Borowski
Symphony	Rich Loose
Systematic Designs	Jack Griffith
Technology Performance Group	Wanda Mattson
Teradyne	Brian Amero
Teradyne	Amie Gray
Teradyne	Tom Henry
Teradyne	Frank Kennedy
Teradyne	Gerry McMahan
Therma-Wave, Inc.	Rakesh Khanijow
TI	Vallabh Dhudshia
TI	Chris Atkinson
TI	J.E. Patrick Gagnon
Tokyo Electron Ltd.	Todd Karasawa
Tokyo Electron Ltd.	Katsuhiko Matsuda
Tokyo Electron Ltd.	Makoto Miyagi
Tokyo Electron Ltd.	Takuya Mori
Tokyo Electron Ltd.	Yasuhiro Okumoto
Tokyo Electron Ltd.	Ray Peterson
Tokyo Electron Ltd.	Shinichi Shinozuka
Tokyo Electron Ltd.	Satoshi Tochiori
Tokyo Electron Ltd.	Yoshiyuki Yamaguchi
Varian Semiconductor	Gary Viviani
Zellweger Analytics, Inc.	Ronald Walczak

*Information Based on Registered Sign-in 10/19/2000*